

Fabrication and characterization of a new piezoelectric polymer film

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ABSTRACT

Because of the piezoelectric effect between the electric and mechanical coupling the piezoelectric materials, have been used extensively in recent years. Modern engineering and scientific materials have developed from early structural materials to the modern multi-functional materials. The piezoelectric material have the functions such as investigation, sensing and actuating, and have been applied to the engineering of microelectromechanical system. Compared with the early piezoelectric materials, the polymer materials have many advantages, such as easy to manufacture, low cost and flexible. So the polymers have been developed as the major new-type piezoelectric materials in recent years. In this paper, we use Cyclic Olefin Copolymer material to make a thin electrode layer of COC. Then the COC layer is poling by high voltage field and it ' s piezoelectric properties are measured. Discussions are made to the obtained results.

Keywords : COC ; electrets ; electrets polymer

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